

FORM PTO-1449 (MODIFIED)

LIST OF PUBLICATIONS FOR
APPLICANT'S INFORMATION
DISCLOSURE STATEMENT

Applicant(s): Allen et al.
Docket No.: YOR920030175US1
Serial No.: 10/661,041
Filing Date: September 12, 2003
Group: 2811

U.S. PATENT DOCUMENTS

EXAMINER					FILING DATE
INITIAL	DOCUMENT NO.	DATE	NAME	CLASS/SUBCLASS	IF APPROPRIATE
<u>an</u>	5,753,418	05/19/98	Tsai et al.	430/313	
<u>an</u>	6,009,888	01/04/00	Ye et al.	134/1.3	
<u>an</u>	6,316,167	11/13/01	Angelopoulos et al.	430/313	
<u>an</u>	6,387,798	05/14/02	Loke et al.	438/623	
<u>an</u>	6,514,867	02/04/03	Hui et al.	438/713	

FOREIGN PATENT DOCUMENTS

EXAMINER					TRANSLATION
INITIAL	DOCUMENT NO.	DATE	COUNTRY	CLASS/SUBCLASS	YES NO
	EP 0 236 220 A1	13/04/88	Europe		

OTHER DOCUMENTS

EXAMINER					
INITIAL	REF NO.	AUTHOR	TITLE	DATE	PERTINENT PAGES, ETC.
		Celii et al.,	"Process Characterization for Tapered Contact Etch,"	J. Vac. Sci. Technol. B 19(5),	
		American Vacuum Society,	Pgs. 1845-1851 (Sept/Oct 2001).		
		Mahorowala et al.,	"Tunable Anti-Reflective Coatings with Built-In Hard Mask Properties		
		Facilitating Thin Resist Processing,"	Proceedings of the SPIE, Vol. 4343, Pgs. 306-316 (2001).		

Examiner

Date Considered

Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.